

<b>Notice of References Cited</b>	Application/Control No. 10/731,260	Applicant(s)/Patent Under Reexamination LORENZ, GUNAR	
	Examiner Paul Dinh	Art Unit 2825	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"Model Library and Tool Support for MEMS simulation" by Peter Schwarz and Peter Schneider, Conference on "MICROELECTRONIC and MEMS Technology", Edinburgh, Scotland, SPIE Proceedings Series volume 4407, pages 1-14, 2001
	V	
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